

## EAST Search History

## EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S119	23	S117 not S118	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 14:05
S118	5	(US-20030078738-\$ or US-20040078319-\$ or US-20040102934-\$ or US-20050016947-\$).did. or (US-5719796-\$ or US- 6571371-\$ or US- 6615097-\$ or US- 6628809-\$ or US- 6643616-\$ or US- 6728591-\$ or US- 6757645-\$ or US- 6763277-\$ or US- 6774998-\$ or US- 6802045-\$ or US- 6812045-\$ or US- 6905895-\$).did. or (US- 5866437-\$ or WO- 200177979-\$ or WO- 200277589-\$ or US- 20030135302-\$ or US- 20040078319-\$ or US- 20050010319-\$).did.	US-PGPUB; USPAT; DERWENT	OR	OFF	2010/12/15 14:05
S117	28	(US-20040078319-\$ or US-20050016947-\$ or US-20030078738-\$ or US-20040102934-\$ or US-20030101251-\$ or US-20050010319-\$).did. or (US-6774998-\$ or US- 6615097-\$ or US- 5719796-\$ or US- 6757645-\$ or US- 6643616-\$ or US- 6802045-\$ or US- 6763277-\$ or US- 6571371-\$ or US- 7107571-\$ or US- 6728591-\$ or US- 6812045-\$ or US- 6628809-\$ or US-	US-PGPUB; USPAT; DERWENT	OR	ON	2010/12/15 14:05

		6905895-\$ or US- 6198980-\$ or US- 6263255-\$ or US- 7333871-\$ or US- 6810296-\$ or US- 5583780-\$.did. or (US- 5866437-\$ or US- 20040078319-\$ or WO- 200277589-\$ or US- 20050010319-\$ or WO- 200177979-\$ or US- 20030135302-\$.did.				
S116	1	"5583780".pn.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 12:18
S115	18	("20020051567"   "20020082738"   "20020088952"   "20020192966"   "20030097198"   "3614640"   "4578648"   "5396433"   "5482881"   "5810928"   "5838445"   "6020264"   "6409576"   "6486492"   "6594598"   "6638778"). PN. OR ("6810296"). URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 12:04
S114	822	(furnace etch CVD (chemical adj Vapor adj deposition)) near2 model \$4 and semiconductor	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:55
S113	71	((ANDREJ) near2 (MITROVIC)).INV.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 11:49
S112	107	((ERIC) near2 (STRANG)).INV.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 11:49
S111	38	(geometric physical dimension) with semiconductor with (equipment device tool) adj (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:41
S110	12	("20020133801"   "5590063"   "6530069"   "6581029").PN. OR ("6802045").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 11:39

S109	73	(geometric physical dimension) with (equipment furnace CVD (chemical adj Vapor adj deposition)) adj (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:36
S108	4	S104 and (geometric physical dimension) with (equipment furnace CVD (chemical adj Vapor adj deposition)) adj (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:35
S107	124	S104 and (geometric physical dimension) with (equipment furnace CVD (chemical Vapor deposition)) adj (model \$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:34
S106	120	S104 and (geometric physical dimension) with (furnace CVD (chemical Vapor deposition)) adj (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:33
S105	1424	S104 and (geometric physical dimension) with (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:32
S104	6990	S100 OR S101 and (semiconductor adj tool near3 model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:32
S103	6993	S100 OR S101 and (semiconductor adj tool)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:31
S102	7259	S100 OR S101 and (semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:31

S101	1367	furnace near2 model\$4	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:31
S100	6990	(CVD (chemical Vapor deposition)) near2 model \$4	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:30
S99	19	US-6571371-\$.DID. OR US-6763277-\$.DID. OR US-6529789-\$.DID. OR US-6628809-\$.DID. OR US-6728591-\$.DID. OR US-6774998-\$.DID. OR US-20050010319-\$.DID. OR US-20040044513-\$. DID. OR US-6615097-\$. DID. OR US-6618856-\$. DID. OR US-5539652-\$. DID. OR US-6581029-\$. DID. OR US- 20030003607-\$.DID. OR US-5377116-\$.DID. OR US-5629877-\$.DID. OR US-6625497-\$.DID. OR US-6185472-\$.DID. OR US-7047095-\$.DID. OR US-6587744-\$.DID.	US-PGPUB; USPAT	OR	ON	2010/12/14 15:02
S98	0	(spatially adj resolved) with ((furnace CVD) near2 model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:39
S97	9	((spatially adj resolved) near3 model\$4) and (semiconductor) with tool	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:37
S96	139	(spatially adj resolved) and (semiconductor) with tool	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:36

S95	1556	(spatially adj resolved) and (semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:36
S94	4333	(spatially adj resolved)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:36
S93	2	"6263255".pn.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:32

**EAST Search History (Interference)**

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**12/ 15/ 2010 4:02:12 PM****C:\Documents and Settings\asaxena\My Documents\EAST\Workspaces\10673138.wsp**